Elettronica CMOS 65 nm

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INFN

- The AM chip
- 2 The CHIPIX65 Blocks
- 3 Design in 65 nm CMOS
- 4 Radiation Hardness
- 5 Design problems and solutions

The Associative Memory working principle



- Small Content-Addressable Memory (CAM) cell for each bus and for each pattern
- The CAM cell compares its own content with the hits received
- Matching result (1 or 0) is stored into a Flip-flop (FF)
- Partial matches are analyzed by the majority logic and compared to the desired threshold
- A priority encoder reads the matched patterns in order

AM Chip History

Vara

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	vers.	Design	recn.	Aica	1 allerns	I achage
	1	Full custom	700 nm		128	QFP
	2	FPGA	350 nm		128	QFP
	3	Std cells	180 nm	100 mm ²	5 k	QFP
	А	Std cells +	65 nm	14 mm^2	8 k	OEP
	mini-5	Full custom	05 1111	14 11111	UK	QII
		Std cells +		4 mm^2	በፍレ	OEP
	iiiii-J	Full custom	65 nm	4 11111	0,5 K	QUI
	5	+ IP blocks		12 mm ²	3 k	BGA
		Std cells +				
	6	Full custom	65 nm	168 mm ²	128 k	BGA
		+ IP blocks				
	7a	Full custom		0,6 mm ²	2,3 k	CQFP
	7b	Full custom	28 nm	9,7 mm ²	38 k	SIP BGA
		+ Std cells				

Tach

Araa

Dattarna

Dackage

blue = under design (figures are estimated)

The AM06 Chip





AM06 is a **large** silicon chip in TSMC CMOS 65 nm technology:

- 168 mm²
- 421 M transistors
- 64 blocks, each of them containing 2 kbit of Associative Memory (AM), designed with full-custom approach and employing a new AM cell (XORAM) specifically optimized for FTK
- SERDES (serializer/deserializer) IP blocks from Silicon Creations, for serial I/O at 2 Gbit/s
- Standard cell 'glue' logic, JTAG interface, and BIST (CRC)

CHIPIX65 1st demonstrator chip



Layout:

3 256 \times 256 SRAM arrays based on DICE (Dual Interlocked CEII) + other cells

V. Liberali (UniMI + INFN)

D2RA: Double-Rail Redundant Approach

Idea: uso di logica ridondante con bit e bit negato



V. Ciriani, L. Frontini, V. Liberali, S. Shojaii, A. Stabile, G. Trucco: "Radiation-tolerant standard cell synthesis using double-rail redundant approach", in *Proc. of Int. Conf. on Electronics, Circuits and Systems (ICECS)*, Sept. 2014, http://dx.doi.org/10.1109/ICECS.2014.7050063

Porte logiche D2RA: AND / NAND schematic





Porte logiche D2RA: AND / NAND layout





65 nm gates require PCM (Phase Change Masks)

Conventional masks for photolithography are *binary* masks:

- 0 = opaque
- 1 = transparent

Phase Change Masks are ternary masks:

- 0 = opaque
- 1 = transparent with phase = 0 \circ
- -1 = transparent with phase = 180 \circ

The 65 nm gate is defined by an opaque strip, with two different phases on the S and D sides

 \longrightarrow ALL transistor gates MUST have the same orientation!

Reduction of transistor size requires the reduction of metal width for scaling Consequences:

- The metal height is larger than width
- Metal resistance cannot be neglected (tens of milliohm per square)
- Lateral capacitance is much larger than vertical capacitance

Propagation delay is limited by RC parasitics of interconnections

Dynamic power consumption due to interconnection does not scale (and will increase for ultra-scaled technologies.

An example: at 20 nm technology node

- the energy required for boolean operations is about one attojoule per bit
- The energy required to transport 1 bit of information is about one picojoule per millimeter

Total Dose Effects

From Federico Faccio's talk at the RD53 meeting (CERN, Apr. 2016):

Radiation-Induced Narrow Channel Effect (RINCE) Radiation-Induced Short Channel Effect (RISCE)



Vertical axis: % loss of current (-100% \rightarrow transistor is died!) Narrow and short transitors are more damaged by total dose!

RINCE: Radiation Induced Narrow Channel Effect

From Federico Faccio's talk at the RD53 meeting (CERN, Apr. 2016):

W=min size

W=moderate size









RISCE: Radiation Induced Short Channel Effect

From Federico Faccio's talk at the RD53 meeting (CERN, Apr. 2016):





Which defect? Which charge trapped? Where?



L=min size



Latch-up

Warning! For very high radiation hardness, guard rings must be placed **all around active devices**, to block parasitic currents. Remember that the latch-up can be triggered **either** by the voltage **or** by the current. Low V_{DD} (≈ 1 V) helps, but does not guarantee latch-up immunity!



Thyristor or SCR (silicon-controlled rectifier) VI characteristics, from: S.M. Sze and K.K. Ng, Physics of Semiconductor Devices, John Wiley & Sons, 2007.

Main issues:

- © Chip composition and design verification require time!
 - Our experience: about two working days are required for the chip composition and the final verfication of a small design (2 mm \times 2 mm)
 - A large chip requires at least one week, or more

Serve powerful new CAD tools!

- EAD (Electrical Advanced Design) provides semi-automatic routing, on-line LVS and DRC, and information on interconnection parasitics during layout design
- Powerful sign-off tools: Voltus (IR drop) and Tempus (timing)
- Caution: for designs with mixed approach (e.g., full custom + standard cells), 'Liberty' files should be provided for all blocks

© The complete **TSMC 65 nm library provided by CERN** is very helpful!

- Full DRC and LVS are possible (including transistors in std cells)
- ESD protection check can be performed (included in DRC)
- Caution: design rules are different for devices directly connected to pads